

CONTROLLING APPARATUS, SUBSTRATE PROCESSING APPARATUS, METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE, AND PROGRAM

ABSTRACT

There is provided a technique that includes: a recipe including a plurality of steps for which a processing condition for a substrate is defined; a display capable of displaying at least one selected from information on the plurality of steps included in the recipe and information on the processing condition of at least one step selected from the plurality of steps; an operator configured to perform an editing operation for the processing condition; and a controller capable of controlling information on a step for which the editing operation for the processing condition is performed to be displayed in a different manner from information on a step for which the editing operation is not performed.

Fig. 3